# 半导体物理B

# **Semiconductor Physics B**

程骏骥

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试画出掺杂为 $N_A$ 的p型半导体处于强电离区的电荷分布图,并求出其载流子浓度和费米能级。

答:

$$E_c$$

$$E_A$$
  $p_A$ 
 $E_v$   $p_0$ 

由电中性方程得:  $p_0 = N_A$ 

再由质量作用定律得:

$$n_0 = n_i^2 / N_A$$

代入平衡载流子浓度方程  $p_0 = N_v \cdot e^{-\frac{E_F - E_v}{k_0 T}}$ 

得: 
$$E_F = E_v - k_0 T \ln(N_A/N_v)$$

(1) 某Si中,每百万个Si原子掺有一个p型杂质原子,计算室温下材料中少数载流子的浓度。(已知Si晶体的原子密度为 $4.96 \times 10^{22}$  cm<sup>-3</sup>, $n_i$  =  $1.5 \times 10^{10}$  cm<sup>-3</sup>)

解: (1) 
$$N_A$$
 = (4.96×10<sup>22</sup>) × 10<sup>-6</sup>  
= 4.96×10<sup>16</sup> (cm<sup>-3</sup>) >> 10 $n_i$ 

所以 
$$p_0 \approx N_A = 4.96 \times 10^{16}$$
 (cm<sup>-3</sup>)

故少数载流子的浓度

$$n_0 = \frac{n_i^2}{p_0} = \frac{(1.5 \times 10^{10})^2}{4.96 \times 10^{16}} \cong 4.5 \times 10^3 (\text{cm}^{-3})$$

- (1) 某Si中,每百万个Si原子掺有一个p型杂质原子,计算室温下材料中少数载流子的浓度。(已知Si晶体的原子密度为 $4.96 \times 10^{22}$  cm<sup>-3</sup>, $n_i$  =  $1.5 \times 10^{10}$  cm<sup>-3</sup>)
- (2) 温度升到573K时, $n_i \approx 3 \times 10^{15}$  cm<sup>-3</sup>,设掺入的杂质浓度不变,问此时半导体呈现什么导电性? 电子与空穴的浓度大致等于多少?

(2) 573K时,

由电中性条件: 
$$n_0 + N_A = p_0$$

及质量作用定律:  $n_0 p_0 = n_i^2$ 

得到 
$$p_0 \approx ??? \times 10^{16} \,\mathrm{cm}^{-3}$$

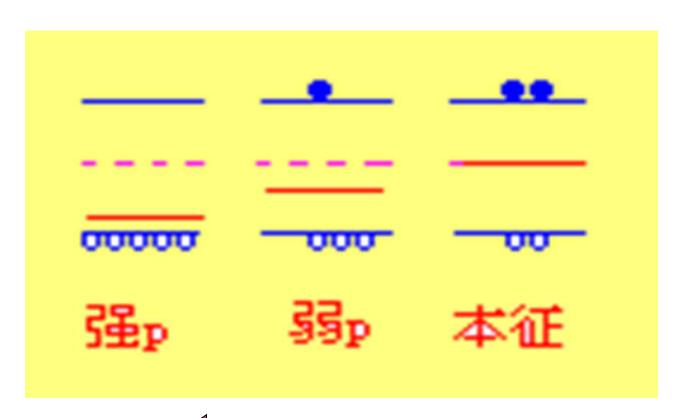
所以 
$$n_0 = ??? \times 10^{14} \,\mathrm{cm}^{-3}$$

可见, 
$$p_0 > n_0$$

因此, 半导体仍呈现为p型导电性.

- (1) 某Si中,每百万个Si原子掺有一个p型杂质原子,计算室温下材料中少数载流子的浓度。(已知Si晶体的原子密度为 $4.96 \times 10^{22}$  cm<sup>-3</sup>, $n_i$  =  $1.5 \times 10^{10}$  cm<sup>-3</sup>)
- (2) 温度升到573K时, $n_i \approx 3 \times 10^{15} \, \mathrm{cm}^{-3}$ ,设 掺入的杂质浓度不变,问此时半导体呈现什么 导电性? 电子与空穴的浓度大致等于多少?
- (3) 画出室温下该p型Si的能带图, 当杂质原子浓度增加时, 费米能级将如何变化?

(3) 当杂质原子浓度增加时



杂质原子浓度增加

To calculate the thermal-equilibrium electron and hole concentration in a germanium sample with a given doping concentration.

Consider a germanium sample at T = 300 K in which  $N_{\rm D} = 5 \times 10^{13}$  cm<sup>-3</sup> and  $N_{\rm A} = 0$ .

Assume that now  $n_i = 2.4 \times 10^{13}$  cm<sup>-3</sup>.

#### Solution:

From 
$$\begin{cases} n_0 = N_D + p_0 \\ n_0 p_0 = n_i^2 \end{cases}$$

Then 
$$n_0 = \frac{N_D}{2} + \frac{\sqrt{N_D^2 + 4n_i^2}}{2}$$

$$= \frac{5 \times 10^{13}}{2} + \frac{\sqrt{(5 \times 10^{13})^2 + 4(2.4 \times 10^{13})^2}}{2}$$
  
\$\approx 5.97 \times 10^{13} (cm^{-3})\$

$$p_0 = \frac{n_i^2}{n_0} = \frac{(2.4 \times 10^{13})^2}{5.97 \times 10^{13}} = 9.65 \times 10^{12} (\text{cm}^{-3})$$

To determine the required donor impurity concentration to obtain a specified  $E_F$ .

Silicon at T=300 K contains an acceptor impurity concentration of  $N_A=10^{16}$  cm<sup>-3</sup>. Determine the concentration of donor impurity that must be added so that the silicon in n type and the Fermi energy is 0.20 eV below the conduction band edge.  $N_c=2.8\times10^{19}\,\mathrm{cm}^{-3}$ .

#### **Solution:**

**From** 

$$n_{0} = N_{c} \cdot e^{\frac{E_{c} - E_{F}}{k_{0}T}}$$

$$= 2.8 \times 10^{19} \cdot \exp\left(-\frac{0.20}{0.0259}\right)$$

$$= 1.24 \times 10^{16} \left(cm^{-3}\right)$$

$$\gg n_{i}$$

We have  $N_D - N_A = n_0$ 

Then

$$N_D = 1.24 \times 10^{16} + N_A = 2.24 \times 10^{16} (cm^{-3})$$

To determine the Fermi-level position and the maximum doping concentration at which the Boltzmann approximation is still valid.

Consider p-type silicon, at T=300K, doped with boron. We may assume that  $E_A - E_V = 0.045$  eV and the limit of the Boltzmann approximation occurs when  $E_F - E_A = 3k_0T$ .

 $n_i = 1.5E10 \text{ cm}^{-3}$ .

# •Solution: If we assume that $E_{Fi} \approx E_{i}$ ,

from 
$$N_{A} \approx P_{0} = n_{i} \cdot e^{-\frac{E_{F} - E_{i}}{k_{o}T}}$$
Then 
$$N_{A} = n_{i} \cdot e^{-\frac{E_{F} - E_{i}}{k_{o}T}}$$

$$= n_{i} \cdot e^{\frac{\frac{E_{g}}{2} - (E_{A} - E_{v}) - (E_{F} - E_{A})}{k_{o}T}} = \cdots = 3 \times 10^{17} \ (cm^{-3})$$

例: 判断并予以修正、给出正确问题和答案:

- \*为什么禁带宽度越宽,掺杂浓度越高,相应器件的极限工作温度就越高?
- \*提示:如果掺杂使得半导体成为简并半 导体,则掺杂浓度越高将导致禁带越窄.
- \*一定温度的非简并半导体,禁带宽度越宽, $n_i$ 越小,掺杂浓度越高, $n_D^+$ 或 $n_A^-$ 越大,升高温度方可使 $n_i$ 超过 $n_D^+$ 或 $n_A^-$

设两块n型硅的施主浓度分别为 $1.5 \times 10^{14}$  cm<sup>-3</sup>及 $10^{12}$  cm<sup>-3</sup>,试分别计算它们500 K时的 $n_0$ 与 $p_0$ 。

已知500 K时Si的
$$n_i = 3.5 \times 10^{14}$$
 cm<sup>-3</sup>

解:

500 K时硅中施主已全部电离,故:

$$\begin{cases} n_0 = N_D + p_0 \\ n_0 p_0 = n_i^2 \end{cases}$$

#### 例题

求解上述方程组, 得:

$$\begin{cases} n_0 = \frac{N_D}{2} \left( 1 + \sqrt{1 + \frac{4n_i^2}{N_D^2}} \right) \\ p_0 = \frac{n_i^2}{n_0} \end{cases}$$

代入:  $N_D = 1.5 \times 10^{14} \text{ cm}^{-3}$  和  $n_i = 3.5 \times 10^{14} \text{ cm}^{-3}$ 

得:  $n_0 \approx 4.3 \times 10^{14} \text{ cm}^{-3}$ ,  $p_0 \approx 2.8 \times 10^{14} \text{ cm}^{-3}$  差别已不明显

代入:  $N_D = 10^{12} \text{ cm}^{-3}$ 和  $n_i = 3.5 \times 10^{14} \text{ cm}^{-3}$ 

得:  $n_0 = p_0 \approx 3.5 \times 10^{14} \text{ cm}^{-3}$  已到本征温区